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MATEMENT BY APP		Application Number	10/752,092	
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Da Submitted: Augus	+ 18 2004	First Named Inventor	Masatomo SHIBATA	
Day Submitted: Augus	10, 2004	Group Art Unit	2841 2813	
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Sheet 1 o	f 1	Attorney Docket Number	035532-0138	

U.S. PATENT DOCUMENTS

U.S. Patent Document

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		O.S. Faterit Document			Date of Publication of Where Polon	Where Relevant	
Examiner Initials*	Cite No. ¹	Number	Kind Code ² (if known)	Name of Patentee or Applicant of Cited Document	Cited Document MM-DD-YYYY	Passages or Relevant Figures Appear	nt /
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				FOREIGN PATENT DOCUMEN	ITS		
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Examiner	Cite	Foreign Pat	tent Document	Name of Patentee or	Cited Document	Where Relevant/	1
Initials*	No.1	Office ³ Numb	per ⁴ Kind Code ⁵ (if known)	Applicant of Cited Documents	MM-DD-YYYY	Passages or Relevant Figures Appear	T [®]
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Examiner Initials*	Cite No.1			al, serial, symposium, catalog, e			T⁵
initials	140.		-	publisher, city and/or country w	here published.		
	- A1	O. Nam et al	"Lateral epitaxy	of low defect density GaN layer	rs via organometallic va	por phase epitaxy".	
B	1			1, No. 18, 3 November 1997, pa			
13							
1	A2 M. Kuramoto et al., "Room-Temperature Continuous-Wave Operation of InGaN Multi-Quantum-Well Laser						
1				ubstrate with a Backside n-Con	tact", Jpn. J. Appl. Phys	., Vol. 38, Part 2, No.	
	1		999, pages L184		u Uudrida Vanas Dhaas	Caitana with Maid	
1	A3			of Freestanding GaN Wafers b Appl. Phys., Vol. 42, Part 2, No.			1
		Assisted Sepa	nauon , apn. J. A	лурі. Епуз., voi. 42, Fait 2, No.	ואט, וט שמוו. 2005, pa	yes L 1-L3.	

Examiner Signature	205a	Date Considered	7/21/05

T. Zheleva et al., "Pendeo-Epitaxy -- A New Approach for Lateral Growth of Gallium Nitride Structures",

K. Motoki et al., "Preparation of Large Freestanding GaN Substrates by Hydride Vapor Phase Epitaxy

Using GaAs as a Starting Substrate", Jpn. J. Appl. Phys., Vol. 40, Part 2, No. 2B, 15 Feb. 2001, pages

MRS Internet J. Nitride Semicond. Res. 4S1, G3.38 (1999), 6 pages.

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	INFORMATIO	ON DISCLO	SURE	Applicati n Number	Unassigned - 18/752092		
	STATEMENT	T BY APPLI	CANT	Filing Date 01/07/2004			
0	Date Submitted: January 7, 2004			First Named Invent r	Masatomo SHIBATA		
	Date Submitte	u. January	1, 2004	Group Art Unit	Unassigned 28/3		
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Sheet	1	of	1	Attorney Docket Number	035532-0138		

U.S. PATENT DOCUMENTS							
U.S. Patent Document				Date of Publication of	Pages, Columns, Lines, Where Relevant		
Examiner Initials*	Cite No. ¹	Number	Kind Code ² (if known)	Name of Patentee or Applicant of Cited Document	Cited Document MM-DD-YYYY	Passages or Relevant Figures Appear	
02	A1	6,413,627	B1	MOTOKI ET AL.	07-02-2002		
1	A2	2002/0197825	A1	USUI ET AL.	12-26-2002		
	A3	5,290,393		NAKAMURA	03-01-1994		
	A4	2002/0066403	A1	SUNAKAWA ET AL.	06-06-2002		
	A5	6,555,845	B2	SUNAKAWA ET AL.	04-29-2003		
	A6	6,348,096	B1	SUNAKAWA ET AL.	02-19-2002		
V	A7	2003/0080345	A1	MOTOKI ET AL.	05-01-2003		
						- 1	

				FC	DREIGN PATENT DOCUMEN	TS	÷	
		Foreign Patent Document				Date of Publication of Cited Document	Pages, Columns, Lines, Where	1
Examiner Initials*	Cite No. ¹	Offic	e ³ Number ⁴	Kind Code ⁵ (if known)	Name of Patentee or Applicant of Cited Documents	MM-DD-YYYY	Relevant Passages or Relevant Figures Appear	T ⁶
Pa	A8	JP	2003-178984	A	NEC CORP., ET AL.	06-27-2003	//	Abstract
	A9	JP	11-251253	Α	NICHIA CHEM. IND. LTD.	09-17-1999	1	Abstract
	A10	JP	2000-22212	A	SUMITOMO ELECTRIC IND. LTD.	01-21-2000		Abstract
	A11	JP	4-297023	A	NICHIA CHEM, IND. LTD.	10-21-1992	/	Abstract
	A12	JP	10-312971	Α	NEC CORP.	11-24-1998	/	Abstract
V	A13	JP	2003-165799	Α	SUMITOMO ELECTRIC IND. LTD.	06-10-2003		Abstract

	NON PATENT LITERATURE DOCUMENTS							
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